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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

AXEL PREUSSE  
MARKUS NOPPER  
HOLGER SCHÜHRER

Examiner: Edward J. Wojciechowicz

Group Art Unit: 2815

Serial No.: 10/747,722

Att'y Docket: 2000.109700/DE0351

Filed: December 29, 2003

Customer No.: 23720

For: METHOD OF REDUCING WAFER  
CONTAMINATION BY REMOVING  
UNDER-METAL LAYERS AT THE  
WAFER EDGE

**RESPONSE TO OFFICE ACTION DATED NOVEMBER 3, 2004**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450

01/03/2005 6 Alexandria, VA 22313-1450

01 FC:1201 88.00 DA  
02 FC:1202 Sir: 90.00 DA

CERTIFICATE OF MAILING  
37 C.F.R. 1.8

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date below:

November 19, 2004  
Date

*Mary Paul*  
Signature

This paper is submitted in response to the Office Action dated November 3, 2004, for which the three-month date for response is February 3, 2005.

A fee in the amount of \$160.00 is believed to be due in connection with the present paper. The Director is authorized to deduct such fee, and any other fees required under 37 C.F.R. §§ 1.16 to 1.21, from the Advanced Micro Devices, Inc. Deposit Account No. 01-0365/DE0351. In the event the monies in that account are insufficient, the Director is authorized to withdraw funds from Williams, Morgan & Amerson, P.C. Deposit Account No. 50-0786/2000.109700.

Reconsideration of the application in view of the following amendments and remarks is respectfully requested.